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TRANSMITTAL LETTER TO THE UNITED STATES DESIGNATED/ELECTED OFFICE (DO/EO/US) CONCERNING A FILING UNDER 35 U.S.C. 371		U.S. APPLICATION NO. (If known, see 37 C.F.R. 1.5) 10/018489 unknown
INTERNATIONAL APPLICATION NO. PCT/EP00/05758	INTERNATIONAL FILING DATE 21/06/2000	PRIORITY DATE CLAIMED 21/06/1999
TITLE OF INVENTION DETECTOR MODULE FOR AN X-RAY DETECTOR SYSTEM		
APPLICANT(S) FOR DO/EO/US HANSEN, K. et al.		
<p>Applicant herewith submits to the United States Designated/Elected Office (DO/EO/US) the following items and other information:</p> <ol style="list-style-type: none"> <input checked="" type="checkbox"/> This is a FIRST submission of items concerning a filing under 35 U.S.C. 371. <input type="checkbox"/> This is a SECOND or SUBSEQUENT submission of items concerning a filing under 35 U.S.C. 371. <input checked="" type="checkbox"/> This is an express request to begin national examination procedures (35 U.S.C. 371(f)). The submission must include items (5), (6), (9) and (21) indicated below. <input checked="" type="checkbox"/> The U.S. has been elected by the expiration of 19 months from the priority date (Article 31). A copy of the International Application as filed (35 U.S.C. 371(c)(2)). <ol style="list-style-type: none"> <input type="checkbox"/> is attached hereto (required only if not communicated by the International Bureau). <input checked="" type="checkbox"/> has been communicated by the International Bureau. <input type="checkbox"/> is not required, as the application was filed in the United States Receiving Office (RO/US). <input type="checkbox"/> An English language translation of the International Application as filed (35 U.S.C. 371(c)(2)). <ol style="list-style-type: none"> <input type="checkbox"/> is attached hereto. <input type="checkbox"/> has been previously submitted under 35 U.S.C. 154(d)(4). <input checked="" type="checkbox"/> Amendments to the claims of the International Application under PCT Article 34. <ol style="list-style-type: none"> <input type="checkbox"/> are attached hereto (required only if not communicated by the International Bureau). <input checked="" type="checkbox"/> have been communicated by the International Bureau. <input type="checkbox"/> have not been made; however, the time limit for making such amendments has NOT expired. <input type="checkbox"/> have not been made and will not be made. <input type="checkbox"/> An English language translation of the amendments to the claims under PCT Article 19 (35 U.S.C. 371(c)(3)). <input type="checkbox"/> An oath or declaration of the inventor(s) (35 U.S.C. 371(c)(4)). <input type="checkbox"/> A English language translation of the annexes of the International Preliminary Examination Report under PCT Article 36 (35 U.S.C. 371(c)(5)). <p>Items 11 To 20 below concern document(s) or information included:</p> <ol style="list-style-type: none"> <input type="checkbox"/> An Information Disclosure Statement under 37 C.F.R. 1.97 and 1.98. <input type="checkbox"/> An assignment document for recording. A separate cover sheet in compliance with 37 C.F.R. 3.28 and 3.31 is included. <input type="checkbox"/> A FIRST preliminary amendment. <input type="checkbox"/> A SECOND or SUBSEQUENT preliminary amendment. <input type="checkbox"/> A substitute specification. <input type="checkbox"/> A change of power of attorney and/or address letter. <input type="checkbox"/> A computer-readable form of the sequence listing in accordance with PCT Rule 13ter.2 and 35 U.S.C. 1.821-1.825. <input type="checkbox"/> A second copy of the published international application under 35 U.S.C. 154(d)(4). <input type="checkbox"/> A second copy of the English language translation of the international application under 35 U.S.C. 154(d)(4). <input checked="" type="checkbox"/> Other items or information. PTO Form 1449 		

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U.S. APPLICATION NO. <u>10/012489</u> unknown		INTERNATIONAL APPLICATION NO. PCT/EP00/05758		ATTORNEY'S DOCKET NUMBER 35-277	
21. <input checked="" type="checkbox"/> The following fees are submitted:				CALCULATIONS PTO USE ONLY	
BASIC NATIONAL FEE (37 C.F.R. 1.492(a)(1)-(5)): -- Neither international preliminary examination fee (37 C.F.R. 1.482) nor international search fee (37 C.F.R. 1.445(a)(2)) paid to USPTO and International Search Report not prepared by the EPO or JPO\$1040.00 -- International preliminary examination fee (37 C.F.R. 1.482) not paid to USPTO but International Search Report prepared by the EPO or JPO.....\$890.00 -- International preliminary examination fee (37 C.F.R. 1.482) not paid to USPTO but international search fee (37 C.F.R. 1.445(a)(2)) paid to USPTO\$740.00 -- International preliminary examination fee (37 C.F.R. 1.482) paid to USPTO but all claims did not satisfy provisions of PCT Article 33(1)-(4).....\$710.00 -- International preliminary examination fee (37 C.F.R. 1.482) paid to USPTO and all claims satisfied provisions of PCT Article 33(1)-(4).....\$100.00					
ENTER APPROPRIATE BASIC FEE AMOUNT =				\$	890.00
Surcharge of \$130.00 for furnishing the oath or declaration later than <input type="checkbox"/> 20 <input checked="" type="checkbox"/> 30 months from the earliest claimed priority date (37 C.F.R. 1.492(e)).				\$	130.00
CLAIMS	NUMBER FILED	NUMBER EXTRA	RATE		
Total Claims	20	-20 =	0	X	\$18.00
Independent Claims	3	-3 =	0	X	\$84.00
MULTIPLE DEPENDENT CLAIMS(S) (if applicable)					\$280.00
CLAIM FEES ARE NOT BEING PAID AT THIS TIME				TOTAL OF ABOVE CALCULATIONS =	
<input type="checkbox"/> Applicant claims small entity status. See 37 CFR 1.27. The fees indicated above are reduced by 1/2.					0.00
SUBTOTAL =				\$	1020.00
Processing fee of \$130.00, for furnishing the English Translation later than <input type="checkbox"/> 20 <input checked="" type="checkbox"/> 30 months from the earliest claimed priority date (37 C.F.R. 1.492(f)).					130.00
TOTAL NATIONAL FEE =				\$	1150.00
Fee for recording the enclosed assignment (37 C.F.R. 1.21(h)). The assignment must be accompanied by an appropriate cover sheet (37 C.F.R. 3.28, 3.31). \$40.00 per property				+	\$ 0.00
Fee for Petition to Revive Unintentionally Abandoned Application (\$1280.00 - Small Entity = \$640.00)				+	\$ 0.00
TOTAL FEES ENCLOSED =				\$	1150.00
				Amount to be:	
				refunded	\$
				Charged	\$
a. <input checked="" type="checkbox"/> A check in the amount of \$1150.00 to cover the above fees is enclosed. b. <input type="checkbox"/> Please charge my Deposit Account No. 14-1140 in the amount of \$_____ to cover the above fees. A duplicate copy of this form is enclosed. c. <input checked="" type="checkbox"/> The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 14-1140. A duplicate copy of this form is enclosed. d. <input checked="" type="checkbox"/> The entire content of the foreign application(s), referred to in this application is/are hereby incorporated by reference in this application.					
NOTE: Where an appropriate time limit under 37 C.F.R. 1.494 or 1.495 has not been met, a petition to revive (37 C.F.R. 1.137(a) or (b)) must be filed and granted to restore the application to pending status.					
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In X-ray holography, atoms in a material sample to be examined are excited to fluorescence, and the fluorescence radiation from the material sample is recorded by a detector. The electric output signals of the detector, which reflect the interference field which builds up within the material sample, then give information about the three-dimensional structure of

the examined sample material. For this purpose it is however necessary that the highest possible number of measurements be carried out on the material sample.

5 In the past few years, clear progress has been made in the development and production of X-ray detectors which are intended to record the fluorescence radiation of the material sample and separate this reliably from the varied background radiation. These detectors must on the one hand be energy-
10 sensitive, in order to make possible a distinction of the incoming photons according to their energy or the wavelength of the radiation, but on the other hand, make it possible to operate up to such high counting rates that they record some hundreds of thousands of photons per second. For this purpose,
15 in addition to silicon detectors, mostly germanium detectors were used in the past. The latter must however be cooled with liquid nitrogen, which is relatively costly, and are more suited to recording radiation from approximately 10 keV. A further disadvantage in the use of germanium detectors is that
20 the electronics needed to amplify the measurement signals from the germanium detector can only be arranged at a position which is relatively remote from the germanium detector. To couple the germanium detector with the amplification electronics, long connection lines are thus required, which leads to strong
25 interference and to a susceptibility to error. An integration of pre-amplifier stages in the vicinity of the germanium detector has to date not been successful, the costly cooling of the germanium detector representing a major obstacle. In addition, with an integration of the amplification electronics
30 in the vicinity of the germanium detectors, a considerable number of signal lines must be routed away from the germanium detector or from the amplification electronics, which has proved to be an insurmountable obstacle even with smaller detector lines or detector arrays.

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Very recently, progress has also been made in the development and production of location- and energy-resolving

silicon X-ray detectors. Thus for example, the monolithic integration of highly sensitive drift detector cells with field effect transistors based on high-resistance silicon substrates was achieved. This detector type has already been used as a single-cell detector in the field of X-ray holography.

As mentioned above, it is necessary for X-ray holography that as large as possible a number of measurements of the material sample be carried out. In one of the possible concrete measurement processes (measurement process 1), this means that a large number of measurements of the fluorescence radiation of the sample are carried out above the material sample over the solid angle region of a hemisphere above the material sample with an angular resolution in the degree range. With these measurements, it is necessary when using single-cell detectors to displace the detector, by means of a mechanically complex and costly displacement structure, stepwise along various tracks on the semi-spherical surface above the material sample. To be able to detect the characteristic lines within the spectrum with the required accuracy, approximately $2 \cdot 10^6$ entries per solid angle element are for example required. Up to an event rate of approximately 150 kHz, the lines can be determined without major adverse effect on their width. As, for example, 7200 recordings at different solid angles may be required for a complete hologram, a total measurement time of some 24 hours results.

In a second concrete measurement process (measurement process 2) of X-ray holography, the required angular resolution is achieved through different arrival angles of monochromatic X-ray light. An angular resolution of the fluorescence radiation of the sample and thus a displacement of the detector is not required. Due to the abovementioned event-rate

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limitation of single-cell detectors, the same total measurement time results.

It is possible to shorten the long total measurement time by using multi-cell detectors instead of a single-cell detector. Through simultaneous measurement of different angle regions (measurement process 1) or the event rate correspondingly multiplied in the case of multi-cell detectors, (measurement process 2), the total measurement time is reduced by approximately the factor of the number of detector elements. Due to the limited number of cells or elements, all commercial multi-cell germanium detectors neither make costly displacement structures superfluous in measurement process 1 nor make possible a measurement time reduction to less than approximately one hour (both measurement processes). This reduction in measurement time is regarded as insufficient, as both (synchrotron) radiation sources and the detectors are subjected to fluctuations during long-time operation. The material sample itself can also change during this long measurement, for which reason real-time recordings are ideally desired.

In addition to the detailed example of X-ray holography presented here, detectors for X-ray radiation are used in many other measurement methods, for example in X-ray absorption spectroscopy, X-ray diffraction, X-ray fluorescence analysis and many more fields. For reasons comparable with those mentioned above, commercial silicon and germanium detectors limit the measurements in many applications (for example in synchrotron radiation sources) due to the maximum possible event rate of the detectors or the achievable angle or location resolution.

In US 5,041,729, a multi-cell radiation detector is disclosed in which a number of detector elements is arranged in the form of a line. The radiation detector contains a scintillator on the rear side of which 12 lamellar photodiodes

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are arranged in the form of a line alongside each other. A holder is attached to the photodiodes by means of an isolating adhesive so that all 12 photodiodes are covered and an end section of each photodiode is exposed for wiring. The holder consists of a ceramic insulator and is equipped on its rear side with signal lines for each element. The bond-connection surface of each photodiode is connected by a wire bond to the signal lines. The disadvantage of this design is that only a detector line - but not a detector array - can be produced as the type of wiring allows exclusively a linear arrangement of the detector elements. When using a detector line however, a very long measurement time is required. In addition, the detector line must be displaced stepwise by means of a mechanically complex and costly displacement structure to carry out a complete recording.

It is therefore the **object** of the invention to provide a detector system with the help of which the above-mentioned disadvantages of the state of the art are overcome. It is in particular the object of the present invention to provide a detector module with a two-dimensional arrangement of detector elements forming a detector array including the corresponding wiring technique, the simultaneous recording of X-ray light being possible via a location or angular resolution, so that for example in X-ray holography, the otherwise customary

displacement structure is superfluous. A further object of the invention is to make possible a high total event rate of the detector system so that the measurement time is clearly reduced for the same quality of the measurement results, or the quality of the measurement results is increased for the same measurement time.

A detector module with the features of patent claim 1 serves to achieve these objects, and also a detector system constructed from such detector modules with the features of patent claim 29. Advantageous versions of the detector module and of the detector system are the subject of the associated dependent claims.

The basic idea of the present invention is to arrange several detector modules, each containing a number of detector elements, around the material sample to be examined, roughly in the form of a hemisphere. On the basis of such a detector arrangement, significantly shorter measurement times and even the generation of real-time images is possible.

This arrangement of detector elements leads, however, due to the high necessary density of the detector elements, to subsequent problems with regard to the contact between the detector elements and the cooling of the detector modules or of the associated signal-processing electronics. In the case of the detector module according to the invention, detector cells are used which are provided with integrated pre-amplifier electronics on the silicon substrate. As a result, although the length of the signal line tracks between the detector element and the pre-amplifier step is reduced, which leads to a marked reduction in interference, the number of signal lines which must be routed away from the detector element/pre-amplifier arrangement is simultaneously increased.

The arrangement of the detector modules is preferably based on the capped icosahedron structure of C₆₀ fullerene

As explained above, each detector module preferably contains approximately 60 detector elements which form a detector array in areal, side-by-side arrangement, which essentially has the same hexagonal basic shape as the actual detector module. Due to the necessary low-parasitism coupling of the signal-processing electronics for the processing of the analog signals coming from the individual detector elements (highly sensitive drift detector cells which are monolithically integrated with field effect transistors), these signal-processing electronics must be integrated in the vicinity of

the detector elements or of the detector array. Because of the lower self-heating of the individual detector elements and the clearly higher loss consumption of the components of the signal-processing electronics, a thermal decoupling between the signal-processing electronics and the detector array and also a cooling or a good heat dissipation of corresponding heat flows is necessary. A good heat dissipation is achieved by arranging for housing parts of the module body to consist of a material with good heat-conducting properties, preferably graphite. A thermal decoupling of both heat sources is achieved by arranging for heat flows of the two heat sources to take the shortest possible common tracks. The selection of suitable materials and cross-sections between heat sources and heat sink is based on the respective quantities of the heat flows.

The local integration or low parasitism coupling of the signal-processing electronics to the detector array preferably takes place with the help of a conductor track carrier which is arranged directly above the detector array. On this conductor track carrier there would theoretically have to be provided a conductor track for each connection of each detector element, each conductor track having a first end contact in the immediate vicinity of the respective detector connection, in order to be connected to same by a bonding wire, and a second end contact which is located at one end edge of the conductor track carrier, in order to be connected from there to the electronics.

Upon the electric contact between the individual silicon detector elements, in the development presented here with integrated field effect transistor, contact between a total of 6 connections would be necessary for each detector element, and connection with very short bonding wire lengths to the conductor track carrier arranged above the detector elements. In the case of a sensitive surface of approximately 5 mm² for each detector element, a contact with a conventional bonding wire technique is not possible. In addition, the conductor

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polyphenylquinoxalines with a relative dielectric constant of approx. 2.7, but also standard polyimides would be conceivable. A further optimization is achieved by providing the screening conductor tracks located in the metallization plane (detailed description follows) at the same point also in a second metallization plane between the rigid support and the dielectric intermediate layer. Compared with the simplest solution, in which the signal lines are developed directly on a ceramic support, the coupling capacity can be reduced by more than a factor of 30, precisely when there are small gaps between the signal lines (for example approx. 50 μm for conductor track widths of approx. 15 μm).

As mentioned at the outset, the basic idea of the present invention is to arrange several detector arrays or detector modules, each containing a number of detector elements, around the material sample to be examined, roughly in the form of a hemisphere. The hemisphere surface is preferably constructed by an arrangement of several areal detector modules each of which contains several detector elements. The individual detector modules are preferably shaped and arranged such that as complete a coverage of the hemisphere surface as possible is achieved. The use of as few different module forms as possible is preferred. A possible variant is to combine four hexagons and five squares into a tetrakaidecahedron. A further preferred variant is to use a capped icosahedron structure of C_{60} fullerene (buckyball) in which an approximately hemispherical surface is formed from ten hexagons, the five pentagonal free surfaces of which are either closed by suitably inserted pentagons or covered by identical hexagons. With both variants named by way of example, it is preferred to construct the hemispherical surface from identical detector modules, for which reason the quadrangular free surfaces of the tetrakaidecahedron or the pentagonal free surfaces of the icosahedron structure are each covered by the hexagonal base modules, as a result of which only one single module type (a hexagonal detector module) is required with both variants. To

better match the hemispherical surface, it is naturally also possible to use curved detector modules.

In the case of a preferred design of the invention, the abovementioned icosahedron structure is used with which the connections between the individual detector elements and the downstream signal-processing electronics (analog amplifiers etc.) can be kept very short in order to reduce parasitic effects in this manner. The chip(s) which contain the signal-processing electronics are preferably arranged above the detector module and radiometrically screened from the detector array. The connections between the connections of the detector elements of a detector array and the connections of the chips of the signal-processing electronics are produced with the help of a flexible flat cable or a flexible connection film which is led out close to a side edge of the hexagonal detector module.

As already explained above, the preferred detector module has a hexagonal shape and contains approx. 61 connected detector elements. The external edge length of the preferred module is approximately 1.5 cm and the active surface is approximately 3 cm². The proportion of active to passive surface is approximately 50 %, this proportion being dependent on the bonding technique used. In the case of so-called flip-chip contact, a proportion of active to passive surface of approximately 90 % can be achieved. In the case of flip-chip contact, problems can arise due to the different coefficients of thermal expansion of AlN (conductor track carrier) and Si (detector array). A possible solution is the use of silicon also for the conductor track carrier, when a polymer layer for example can then be used as dielectric.

In the case of a preferred sphere radius of the buckyball arrangement of approx. 3.7 cm, an average solid-angle resolution of approx. 4° results. It is apparent that the solid-angle resolution can be increased, while maintaining the detector element surface density, by increasing the hemisphere

radius. However, the total number of detector elements and consequently also the technical outlay required for the processing of the many data channels, also increases at the same time. The solid-angle resolution can also be increased, while maintaining the hemisphere radius, by a reduction in the active surface per detector element (and consequently by an increase in the detector element surface density), limits being set to this miniaturization by the bonding techniques used.

In the following, the invention is described with reference to the drawings in which:

Fig. 1 shows an overall view and a detail of the metallization plane of a detector element;

Fig. 2 shows a view of the chain-bonded detector array (left) and the conductor track carrier (middle) with an array section and also the flexible connection film with a circuit support (right);

Fig. 3 shows an enlarged representation of the conductor track carrier;

Fig. 4 shows a perspective view of a fully-assembled detector module according to the first embodiment of the invention; and

Fig. 5 shows a cross-section view of a detector module according to a second embodiment of the invention.

The left part of Figure 1 shows the overall view of the metallization plane of an individual detector element, and the right-hand part of Figure 1 shows a detail of this metallization plane. In the centre of the detector element are located drain (D) and also gate and source (S) connections of the monolithically integrated field effect transistor (single-sided junction FET: SSJFET). An internal guard ring (IGR) and a

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conductor tracks which are provided on the ceramic conductor track carrier (middle part of Figure 2). The connections R#1 and S of each detector element are guided through the bore lying in each case above the detector element and connected to the associated contact points of the conductor tracks. All conductor tracks on the conductor track carrier open out at one of the six edges of the conductor track carrier (in Figure 2, it is the right-hand edge of the conductor track carrier) and are coupled by wire connections directly or via a flexible connection film to five integrated circuits (front-end chips) which each have 12 analog channels (see right-hand part of Figure 2), where the measurement signals are processed. In addition to the active components, some passive components can also be located on the circuit support.

Figure 3 shows an enlarged representation of the conductor track carrier from Figure 2 which is arranged over the detector array in assembled state of the detector module. Clearly to be seen are the bores for guiding the two bonding wires of the two detector connections of each detector element. The bores are in each case arranged in the assembled state of the detector module above an associated detector element. Provided directly at the edge of these bores, on the surface of the conductor track carrier facing away from the detector array, are in each case two end contacts (output signal connection S and supply voltage R#1) of conductor tracks to which the bonding wires starting from the detector connections and guided out through the associated bores are bound. The conductor tracks then run between the other bores in the direction of the right-hand edge of the conductor track carrier where they end in a row of second end contacts to which a flexible connection film or a rigid circuit support can then be connected.

The arrangement shown in Figure 3 or the course of the conductor tracks from the first end contact to the second end contact is specified precisely so that the individual conductor

tracks are very largely decoupled vis-à-vis conductor tracks running nearby. As can also be seen in Figure 3, so-called screening conductor tracks, each of which lies on the fixed potential R#1, run between the individual signal-carrying conductor tracks, each of which is coupled with the output signal connections S.

Figure 4 shows the overall mechanical structure of the detector module according to the first embodiment of the invention. Shown are the detector array, constructed from the 61 detector elements, with entry windows pointing downwards in Figure 4, and the conductor track carrier arranged above the detector array. The detector array and the conductor track carrier are contained in a hexagonal housing. As explained with reference to Figure 2, four of the six connections of each of the 61 detector elements of the detector array are connected to an external bus structure through simple chain bond connections. To assemble the detector module, the detector array is first inserted into the housing, glued to this and bonded in the form of a chain. The already-equipped arrangement of conductor track carrier and circuit support is secured above the detector array in the housing, the detector array and the conductor track carrier being a uniform distance from one another. The bonding wires provided for the conductor track connection are then guided through the bores and connected to the two free connections of the individual detector elements. At this point the advantages of the invention become particularly clear, as it is easily recognizable that, of the six connections, contact with only two connections through the bores of the conductor track carrier is necessary. The remaining four connections of each detector element are connected by simple chain bond connections, which is mechanically uncritical, as in the case of this production step, the upper contact surface of the detector array is exposed.

In the case of the design of the detector module shown in

Figure 4, the front-end chips and further passive components are provided on a circuit support which is connected directly to the conductor track carriers through wire connections provided the connection lines and the circuit are not jointly realized on a common support.

A much more compact construction of the detector module is shown in Figure 5 in which a cross-section of an alternative design of the detector module is shown. As can be seen in Figure 5, the bonded detector array with the downward-pointing radiation entry windows is inserted into a hexagonal housing (or into the base support) and glued to this. The conductor track carrier is inserted into the housing directly above the detector array (and at a uniform distance from it). In this cross-section view can be seen the bores, provided in the conductor track carrier, through which are guided the two bonding wires for each detector element by means of which the two connections of the respective detector element are connected to associated conductor tracks on the conductor track carrier. As can be seen in Figures 2, 3 and 4, also in the case of the design shown in Figure 5, the conductor tracks provided on the conductor track carrier end at an edge of the conductor track carrier and are connected to a flexible connecting film I at their end points or end contacts. The opposed contacts of the connection film I are connected to a separate circuit support on which all of the analog signal-processing electronics are provided. The components provided on the circuit support are in general relatively radiation-sensitive and must therefore be screened. This is achieved in the design shown in Figure 5 by providing, above the conductor track carrier, already secured in the housing, a radiation shield above which the circuit support provided with the signal-processing electronics is arranged. As can be seen clearly in Figure 5, the flexible connection film I, starting from the conductor, is guided laterally through a gap past the radiation shield to the circuit support. The output signals from the circuit support are then guided through a second flexible

connection film II through the top II, provided above the circuit support, of the detector module to the outside. This second connection film II serves to couple the detector module with an A/D converter module, the digital signal-processing electronics and a computer which further processes the recorded and pre-processed measurement signals. In the concrete example of holography, in the following a hologram of the atomic structure of the examined material sample is presented on a screen.

Not only for reasons of better heat dissipation does the housing of the detector module consist for the most part of graphite. The low-energy position of the carbon fluorescence also permits an extension of the sensitive energy range up to values around 300 eV. Furthermore, shaping considerations also argue for the selection of graphite, as graphite, due to its fine-grained structure, can be worked with low production tolerances of under 50 μm . Optionally, various parts of the housing, such as for example the base support or the tops Ia and Ib, can also consist of aluminium or other metals or else industrial ceramics such as aluminium oxide or aluminium nitride (AlN).

Not all photons are absorbed in the silicon volume of the detector array. Instead, the rate of transmitted photons grows with increasing photon energy. In the case of a layered module structure, as shown in Figure 5, the signal-processing electronics can be damaged by this radiation and the module thus put out of operation. Breakdowns caused by radiation damage can be prevented by embedding of the above-mentioned radiation shield above the detector array. Photons absorbed there excite the screening materials to fluorescence radiation, which is superimposed onto the energy spectrum actually to be detected from the sample. As suitable radiation shield materials, chemically stable materials with atoms of high atomic number are suitable, such as for example tantalum or tungsten, to keep the radiation load of the electronics over

The version of the detector module represented in Figure 5 is particularly suitable for the hemispherical arrangement mentioned at the outset (preferably the capped icosahedron structure of C₆₀ fullerene) around the material sample. A special frame is required for this which, for reasons of better thermal conductivity and screening from external electromagnetic fields and radiation, is made from aluminium. The holder in Figure 5 forms the base element of this frame. In this manner, the individual detector modules can be easily and quickly replaced as required. By using identical, preferably

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Patent claims

1. Detector module for X-ray radiation measurement, with
 - a detector array, which has a first surface, facing a radiation source, which is provided with a number of detector elements, and a second surface, facing away from the radiation surface; and
 - a conductor track carrier which is arranged at a distance from the second surface of the detector array and is provided with conductor tracks;
 - first connections of detector elements which are located on the second surface of the detector array being connected to the conductor tracks with the help of bonding wires;
 - the bonding wires of the first connections of the detector elements being guided through bores in the conductor track carrier onto the side of the conductor track carrier facing away from the detector array, to be connected to the conductor tracks which are developed on the surface of the conductor track carrier facing away from the detector array;
 - a bore being provided in the conductor track carrier for each detector element; and
 - the conductor tracks being guided to signal-processing electronics to process the signals coming from the individual detector elements.
2. Detector module according to claim 1, in which the detector elements are integrated with amplifier electronics.
3. Detector module according to claim 1, in which the detector elements are highly sensitive drift detector cells which are monolithically integrated with field effect transistors.

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4. Detector module according to one of the previous claims, in which second connections of the detector elements are connected by simple chain bonding connections at a bus structure provided on the detector array.
5. Detector module according to claim 4, in which the bus structure is provided at the external edges of the detector array and the bus lines of the bus structure are connected by bonding wires to conductor tracks developed on the conductor track carrier.
6. Detector module according to one of the previous claims, in which the detector array together with the conductor track carrier is mounted in a housing.
7. Detector module according to claim 6, in which the housing is made of a material with high thermal conductivity and low X-ray fluorescence capacity.
8. Detector module according to claim 6 or 7, in which the housing is made of graphite.
9. Detector module according to one of claims 6 to 8, in which the signal-processing electronics are also provided in the housing.
10. Detector module according to one of the previous claims, in which the signal-processing electronics are provided on a circuit support which is arranged on the side of the conductor track carrier facing away from the detector array.
11. Detector module according to one of the previous claims, in which the signal-processing electronics are screened from

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the radiation source by a radiation shield.

12. Detector module according to claim 11, in which the radiation shield is provided between the conductor track carrier and the signal-processing electronics.
13. Detector module according to claim 11 or 12, in which the radiation shield has a first layer of a chemically stable material with atoms of high atomic number, such as for example tantalum or tungsten.
14. Detector module according to claim 13, in which the first layer of the radiation shield has a thickness of more than 300 μm .
15. Detector module according to claim 13 or 14, in which, at the side of the first layer of the radiation shield facing the radiation source, a second layer of a material with atoms of medium atomic number, such as for example titanium, vanadium or chromium, is provided.
16. Detector module according to claim 15, in which the second layer of the radiation shield has a thickness of more than 50 μm .
17. Detector module according to claim 15 or 16, in which, at the side of the second layer of the radiation shield facing the radiation source, a third layer of a material with atoms of low atomic number, such as for example aluminium, is provided.
18. Detector module according to one of the previous claims, in which the conductor track carrier is coupled with the circuit support by means of a flexible connection film (I).

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19. Detector module according to one of the previous claims, in which the conductor track carrier is coupled with the signal-processing electronics by means of a flexible connection film (II).
20. Detector module according to one of the previous claims, which has a hexagonal or pentagonal or quadrangular shape.
21. Detector module according to one of the previous claims, in which contact between the detector array and the conductor track carrier is achieved by means of flip-chip contact.
22. Detector module according to one of the previous claims, in which an intermediate layer the dielectric constant of which is clearly less than that of the carrier material is provided between the mechanically stable carrier material of the conductor track carrier and the signal-carrying metallization plane of the conductor tracks.
23. Detector module according to claim 22, in which the intermediate layer has a thickness which corresponds to approximately the width of a signal-carrying conductor track.
24. Detector module according to claim 22 or 23 in which benzocyclobutenes or polyphenylquinoxalines are used as material for the intermediate layer.
25. Detector module according to one of claims 22 to 24 in which screening conductor tracks are provided in the metallization plan between the signal-carrying conductor tracks, and in which further screening conductor tracks are also provided at the same point in a second metallization plane between the stable carrier material of the conductor

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track carrier and the dielectric intermediate layer.

26. X-ray detector system, with

- a number of detector modules according to one of claims 1 to 28;
- a frame for holding the number of detector modules on an essentially hemispherical surface around a material sample to be examined;
- the essentially hemispherical surface being formed by a capped icosahedron structure.

(12) NACH DEM VERTRAG ÜBER DIE INTERNATIONALE ZUSAMMENARBEIT AUF DEM GEBIET DES
PATENTWESENS (PCT) VERÖFFENTLICHTE INTERNATIONALE ANMELDUNG

(19) Weltorganisation für geistiges Eigentum
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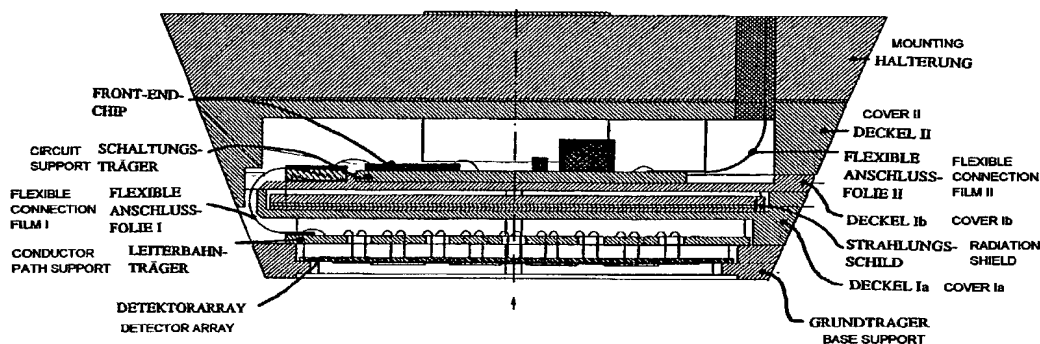
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[Fortsetzung auf der nächsten Seite]

(54) Title: **DETECTOR MODULE FOR AN X-RAY DETECTOR SYSTEM**

(54) Bezeichnung: **DETEKTORMODUL FÜR RÖNTGENDETEKTORSYSTEM**

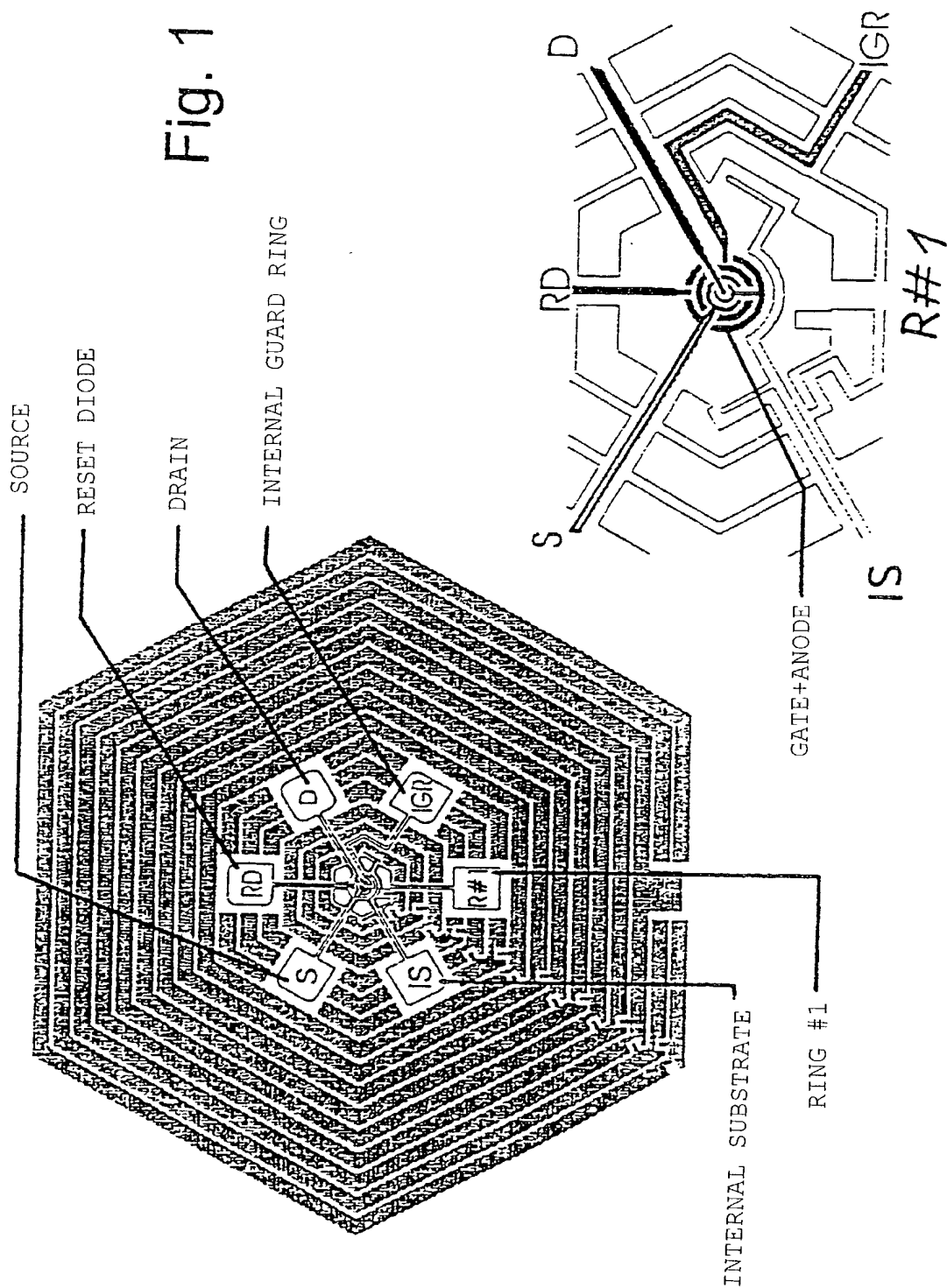


(57) Abstract: The invention relates to a detector module for carrying out an energy-sensitive X-ray measurement. The detector module is equipped with a detector array that comprises a first surface which faces a radiation source and which is provided with a multitude of detector elements, and comprises a second surface which faces away from the radiation source. The detector module is also equipped with a conductor path support which is arranged at a distance from the second surface of the detector array and which is provided with conductor paths. First connections of the detector elements that are located on the second surface of the detector array are connected to the conductor paths with the aid of bonding wires, and the conductor paths are led to a signal processing electronic unit in order to process the outgoing signals from the individual detector elements.

(57) Zusammenfassung: Die Erfindung betrifft ein Detektormodul zur energieempfindlichen Röntgenstrahlungsmessung, mit einem Detektorarray, das eine erste, einer Strahlungsquelle zugewandte Fläche, die mit einer Vielzahl von Detektorelementen versehen ist, und eine zweite, der Strahlungsquelle abgewandte Fläche aufweist; und einem Leiterbahnträger, der beabstandet von der zweiten Fläche des Detektorarrays angeordnet und mit Leiterbahnen versehen ist; wobei erste Anschlüsse der Detektorelemente, die sich an der zweiten Fläche des Detektorarrays befinden, mit Hilfe von Bonddrähte mit den Leiterbahnen verbunden sind; und wobei die Leiterbahnen zu einer Signalverarbeitungselektronik geführt sind, um die von den einzelnen Detektorelementen ausgehenden Signale zu verarbeiten.

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Fig. 1



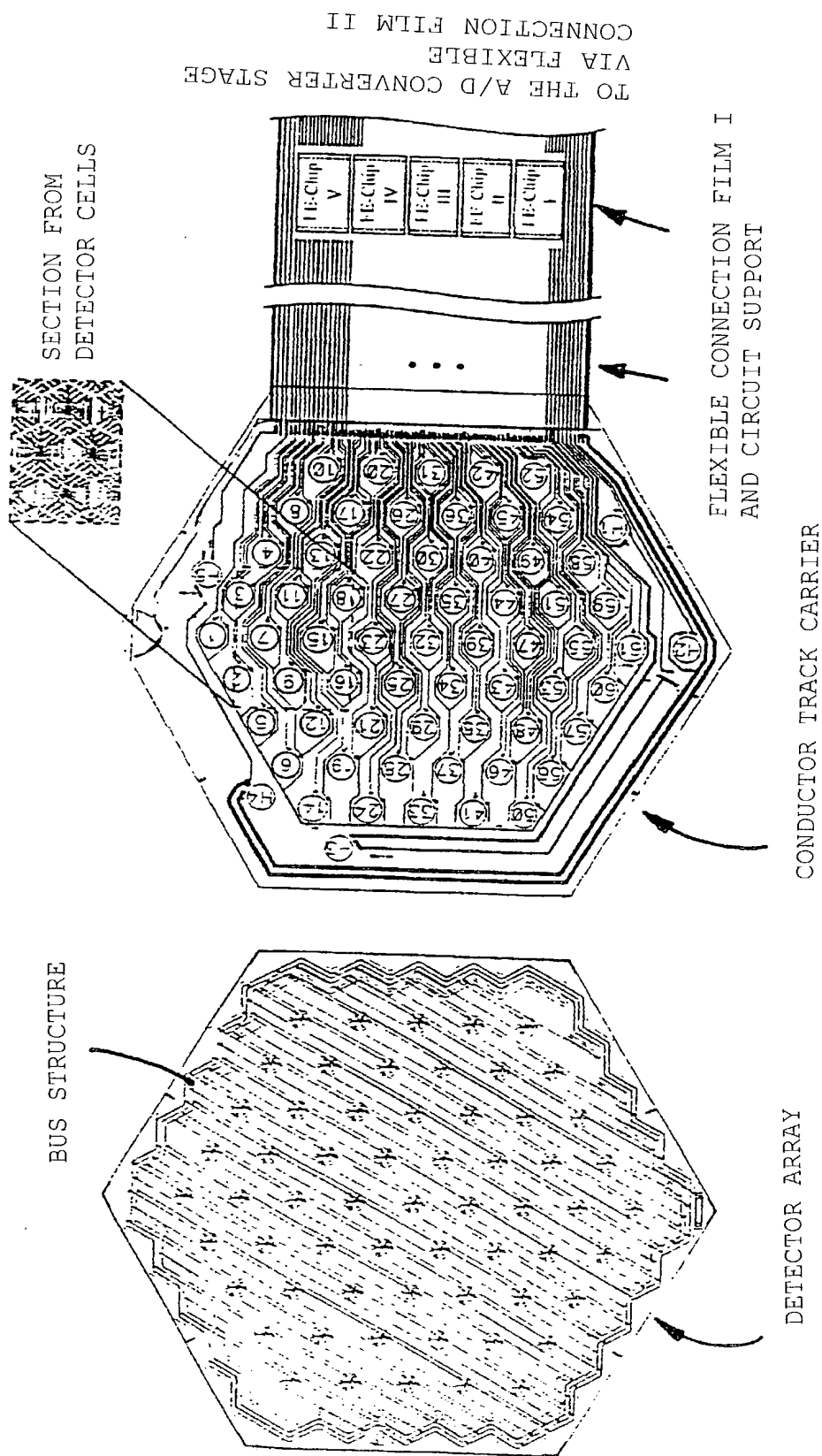
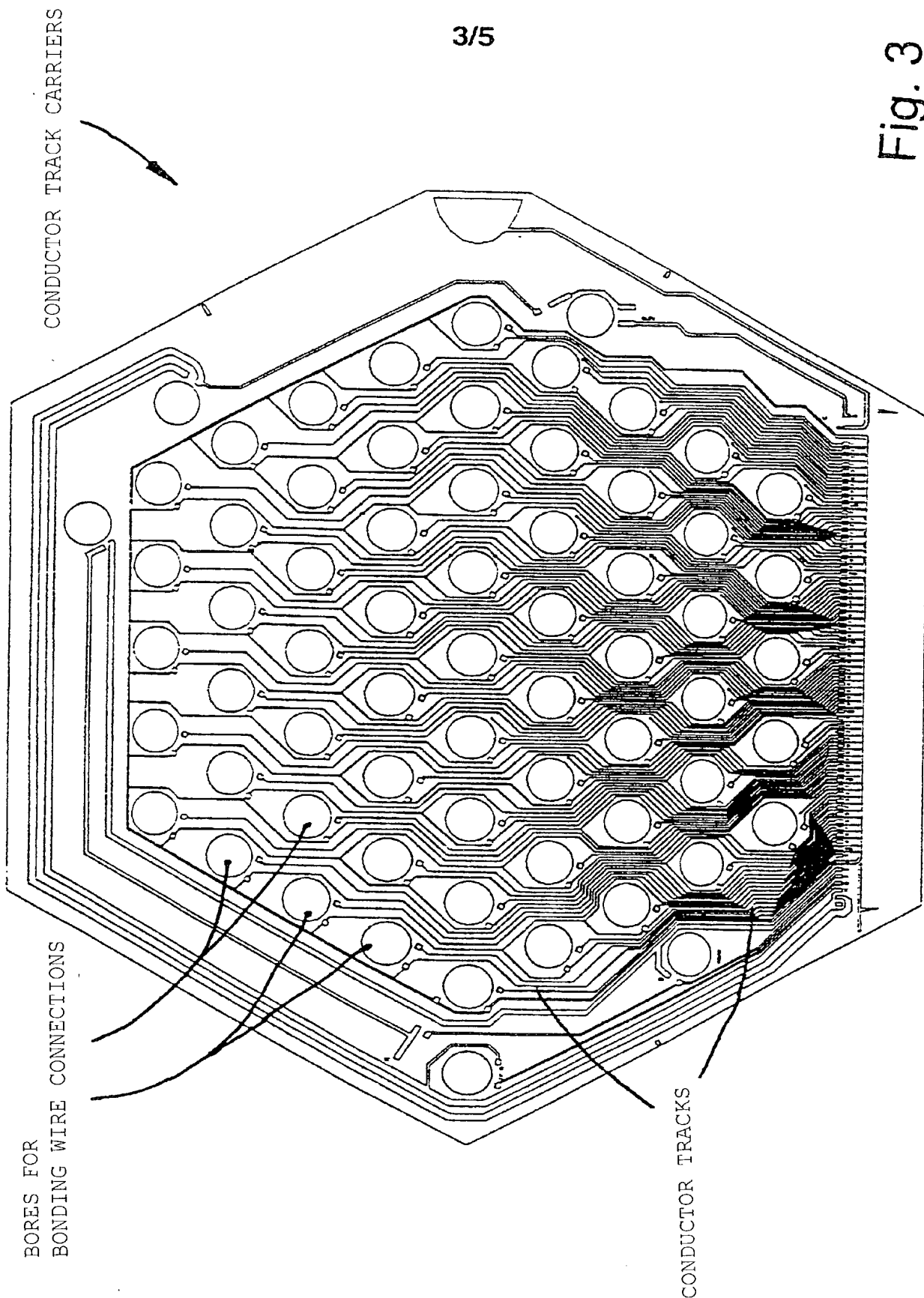


Fig. 2

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Fig. 3



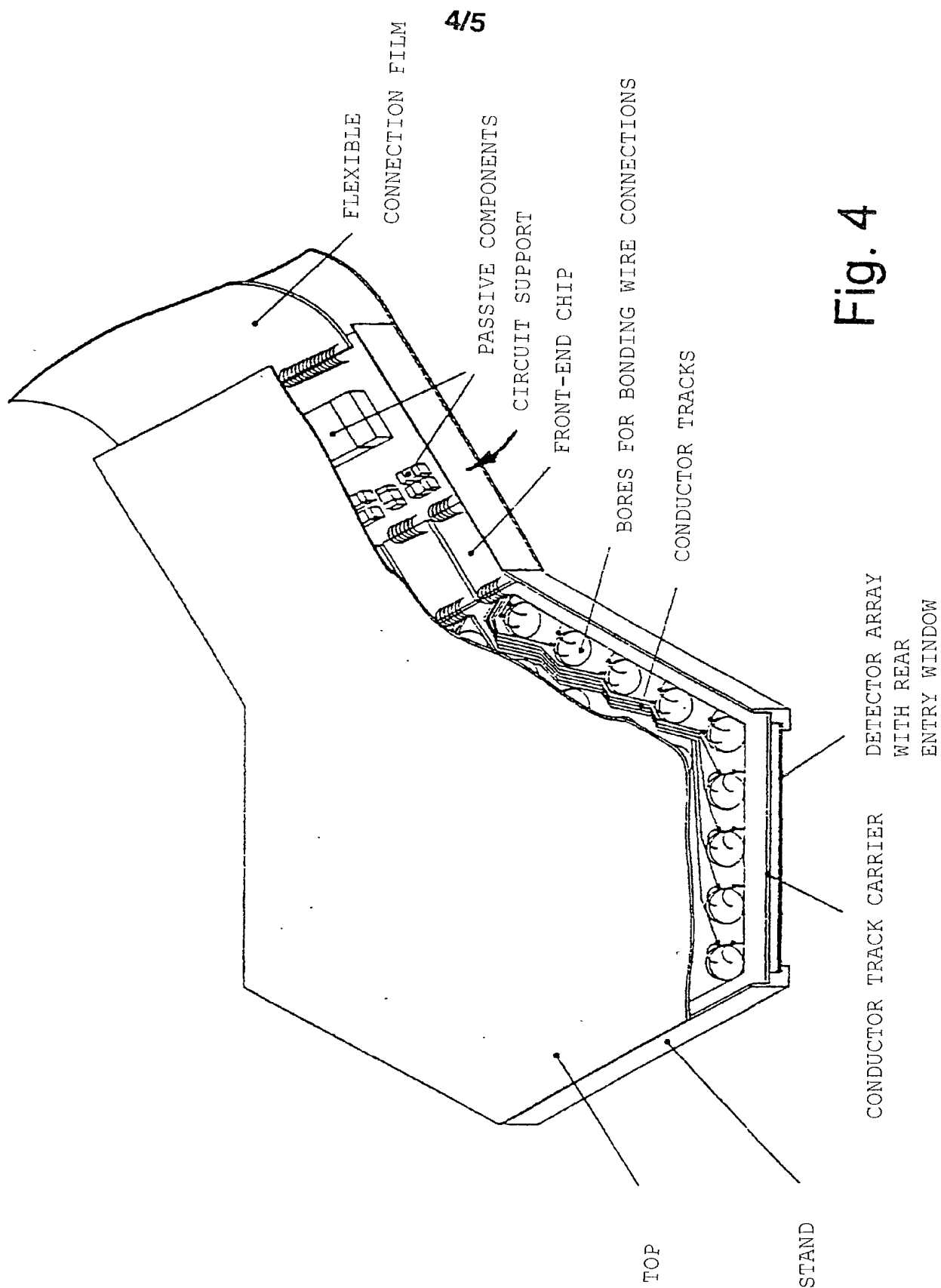


Fig. 4

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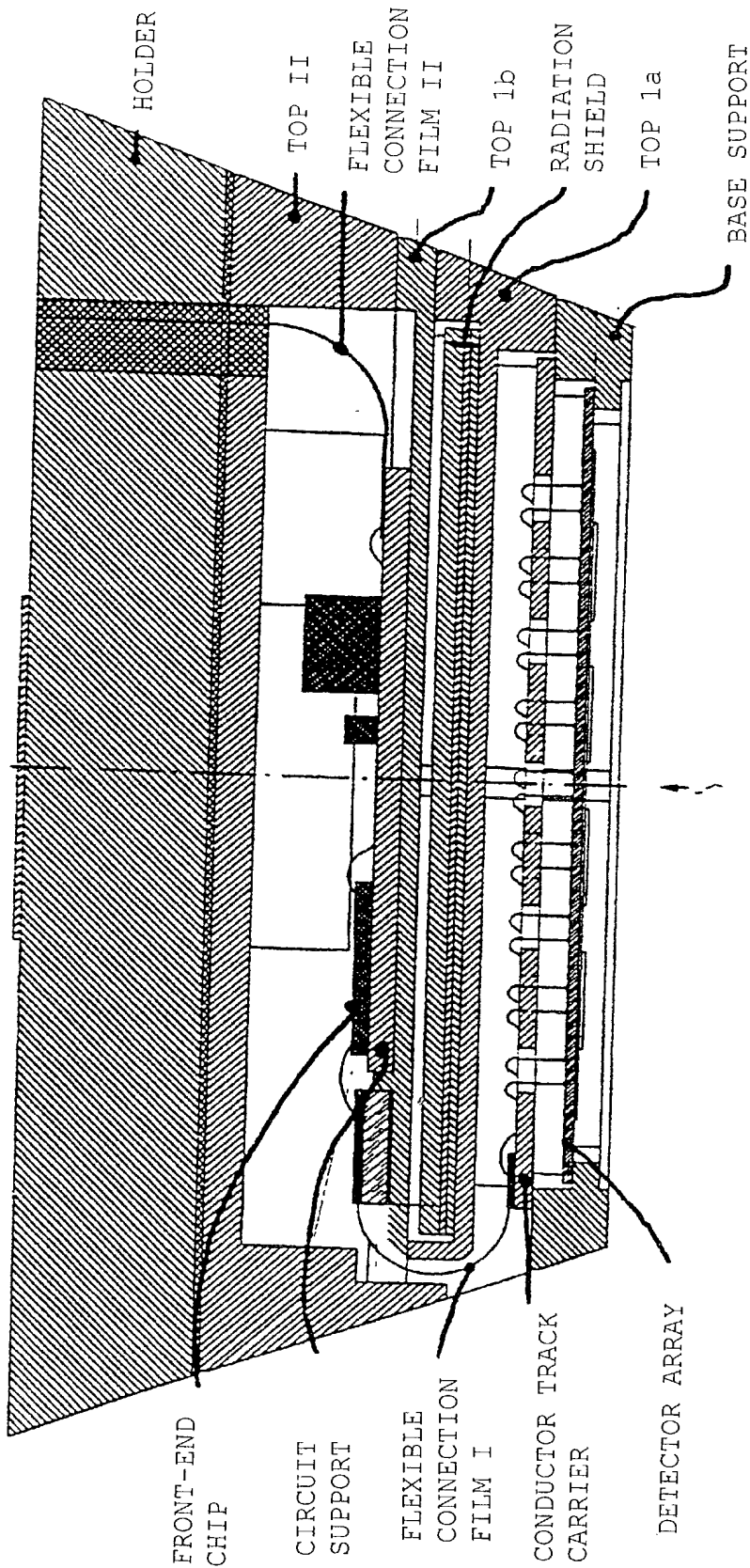


Fig. 5

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(Domestic Non-Assigned/Foreign) Page 1

RULE 63 (37 C.F.R. 1.63)
INVENTORS DECLARATION FOR PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

As a below named inventor, I hereby declare that my residence, mailing address and citizenship are as stated below next to my name, and I believe I am the original, first and sole inventor (if only one name is listed below) or an original, first and joint inventor (if plural names are listed below) of the subject matter which is claimed and for which a patent is sought on the invention entitled:

DETECTOR MODULE FOR AN X-RAY DETECTOR SYSTEM

the specification of which (check applicable box(es)):

☒ is attached hereto
☒ was filed on December 19, 2001 as U.S. Application Serial No. _____ (Atty Dkt. No. 35-227)
☐ was filed as PCT international application No. PCT/EP00/05758 on 21/06/2000
 and (if applicable to U.S. or PCT application) was amended on 11/06/2001

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above. I acknowledge the duty to disclose to the Patent Office all information known to me to be material to patentability as defined in 37 C.F.R. 1.56. I hereby claim foreign priority benefits under 35 U.S.C. 119/365 of any foreign application(s) for patent or inventor's certificate listed below and have also identified below any foreign application for patent or inventor's certificate having a filing date before that of the application on which priority is claimed or, if no priority is claimed, before the filing date of this application:

Application Number	Country	Day/Month/Year Filed
<u>199 29 567.0</u>	<u>DE</u>	<u>21/06/1999</u>

I hereby claim the benefit under 35 U.S.C. §119(e) of any United States provisional application(s) listed below.

Application Number	Date/Month/Year Filed
--------------------	-----------------------

I hereby claim the benefit under 35 U.S.C. 120/365 of all prior United States and PCT international applications listed above or below:

Prior U.S./PCT Application(s): Application Serial No.	Day/Month/Year Filed	Status: patented pending, abandoned
<u>PCT/EP00/05758</u>	<u>21/06/2000</u>	

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon. And on behalf of the owner(s) hereof, I hereby appoint NIXON & VANDERHYE P.C., 1100 North Glebe Rd., 8th Floor, Arlington, VA 22201-4714, telephone number (703) 816-4000 (to whom all communications are to be directed), and the following attorneys thereof (of the same address) individually and collectively owner's/owners' attorneys to prosecute this application and to transact all business in the Patent and Trademark Office connected therewith and with the resulting patent: Larry S. Nixon, 25640; Arthur R. Crawford, 25327; James T. Hosmer, 30184; Robert W. Farris, 31352; Richard G. Besha, 22770; Mark E. Nusbaum, 32348; Michael J. Keenan, 32108; Bryan H. Davidson, 30251; Stanley C. Spooner, 27393; Leonard C. Mitchard, 29009; Duane M. Byers, 33363; Jeffrey H. Nelson, 30481; John R. Lastova, 33148; H. Warren Bumam, Jr., 29366; Mary J. Wilson, 32955; J. Scott Davidson, 33469; Alan M. Kagen, 36178; Robert A. Molan, 29834; B. J. Sadoff, 36683; James D. Berquist, 34778; Updeep S. Gill, 37334; Michael J. Shea, 34725; Donald L. Jackson, 41090; Michelle N. Lester, 32331; Frank P. Presta, 19828; Joseph S. Presta, 35329; Joseph A. Rhoa, 37515; Raymond Y. Mah, 41426; Chris Comuntzis, 31097; Gary T. Tanigawa, 43180. I also authorize Nixon & Vanderhye to delete any attorney names/numbers no longer with the firm and to act and rely solely on instructions directly communicated from the person, assignee, attorney, firm, or other organization sending instructions to Nixon & Vanderhye on behalf of the owner(s).

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☐ See attached sheet(s) for additional inventor(s) information!!